

IDS - 08/20/2004

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention**A METHOD AND SYSTEM FOR INTELLIGENT AUTOMATED RETICLE MANAGEMENT**

Application Number:

Confirmation Number:

First Named Applicant: Richard Burda

Attorney Docket Number: BUR920040031US1

Search string: (6640151 or 5841660 or 4796194 or 6564113 or 6615098 or 20020156548).pn.

US Patent Documents**Note: Applicant is not required to submit a paper copy of cited US Patent Documents**

Init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
SRG	1	6640151	2003-10-28	Somekh, et al			
SRG	2	5841660	1998-11-24	Robinson, et al			
SRG	3	4796194	1989-01-03	Atherton			
SRG	4	6564113	2003-05-13	Barto, et al			
SRG	5	6615098	2003-09-02	Bode, et al			

US Published Applications**Note: Applicant is not required to submit a paper copy of cited US Published Applications**

Init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
SRG	1	20020156548	2002-10-24	Arackaparambil, et al			

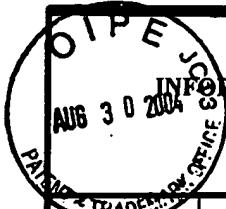
Signature

Examiner Name

Date

/Steven Garland/

08/15/2006



INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)

Docket Number (Optional)	BUR920040031US1	Application Number
Applicant(s)	Burda, et al.	
Filing Date	08/20/04	Group Art Unit Unknown

INITIAL	OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
SRG		Nadoli, et al, "SIMULATION IN AUTOMATED MATERIAL HANDLING SYSTEMS DESIGN FOR SEMICONDUCTOR MANUFACTURING", Proceedings of the 1994 Winter Simulation Conference, pp. 892-899
SRG		Park, et al., "ASSESSMENT OF POTENTIAL GAINS IN PRODUCTIVITY DUE TO PROACTIVE RETICLE MANAGEMENT USING DISCRETE EVENT SIMULATION", Proceedings of the 1999 Winter Simulation Conference, pp. 856-864
SRG		Campbell, et al., "A MODEL OF A 300MM WAFER FABRICATION LINE", Proceedings of the 1999 Winter Simulation Conference, pp. 909-911
SRG		Lee, et al., "DISPATCHING HEURISTIC FOR WAFER FABRICATION", Proceedings of the 2001 Winter Simulation Conference, pp. 1215-1219
SRG		White, Jr., et al., "OPERATIONAL SIMULATION OF AN X-RAY LITHOGRAPHY CELL: COMPARISON OF 200MM AND 300MM WAFERS", Proceedings of the 1999 Winter Simulation Conference, pp. 865-874
SRG		Pierce, et al., "MODELING AND SIMULATION OF MATERIAL HANDLING FOR SEMICONDUCTOR WAFER FABRICATION", Proceedings of the 1994 Winter Simulation Conference, pp. 900-906
SRG		Robinson, et al., "CAPACITY PLANNING FOR SEMICONDUCTOR WAFER FABRICATION WITH TIME CONSTRAINTS BETWEEN OPERATIONS", Proceedings of the 1999 Winter Simulation Conference, pp. 880-887

EXAMINER

/Steven Garland/

DATE CONSIDERED

08/15/2006

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.